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CONFIRMATION NO. 1576

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.		
10/553,573	10/17/2005 RULE	427	1715	Serie 6070		
APPLICANTS Christian Dussarrat, Ibaraki, JAPAN; Jean-Marc Girard, Paris, FRANCE; Takako Kimura, Tsukuba, JAPAN; Naoki Tamaoki, Tokyo, JAPAN; Yuusuke Sato, Tokyo, JAPAN;						
** CONTINUING DATA ***** This application is a 371 of PCT/IB04/01346 04/08/2004						
** FOREIGN APPLICATIONS *****						
** IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 05/30/2006						
Foreign Priority claimed 35 USC 119(a-d) conditions met	<input checked="" type="checkbox"/> Yes <input type="checkbox"/> No <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No	<input type="checkbox"/> Met after Allowance	STATE OR COUNTRY	SHEETS DRAWINGS	TOTAL CLAIMS	INDEPENDENT CLAIMS
Verified and Acknowledged	ELIZABETH A BURKHART Examiner's Signature	Initials	JAPAN	5	18	3
ADDRESS American Air Liquide, Inc. Intellectual Property Dept. 2700 Post Oak Boulevard Suite 1800 Houston, TX 77056 UNITED STATES						
TITLE Methods for producing silicon nitride films by vapor-phase growth						
FILING FEE RECEIVED 1220	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:			<input type="checkbox"/> All Fees		
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